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INFORMATION DISCLOSURE STATEMENT BY APPLICANT				Filing Date	November 17, 2003
				First Named Inventor:	Thomas Hantschel
				Examiner name: <i>C. J. Arbes</i> unknown	GROUP: unknown 3705
Sheet	1	of	1	Attorney Docket Number	A3235 (XCP-035)

U.S. PUBLISHED PATENT APPLICATIONS					
Examiner Initials*	Cited No. <sup>1</sup>	U.S. Patent Document Number	Kind Code <sup>2</sup> (if known)	Name of Patentee or Applicant of Cited Document	Date of Publication of Cited Document MM-DD-YYYY
<i>Op</i>	A01	5944537		Smith et al.	08/31/1999
<i>Op</i>	A02	6183267	B1	Marcus et al.	02/06/2001
<i>Op</i>	A03	6299462	B1	Bielgelsen	10/09/2001
<i>Op</i>	A04	6352454	B1	Kim et al.	03/05/2002
<i>Op</i>	A05	6582989	B2	Biegelsen et al.	06/24/2003

U.S. PATENT DOCUMENTS					
Examiner Initials*	Cited No. <sup>1</sup>	U.S. Patent Document Number	Kind Code <sup>2</sup> (if known)	Name of Patentee or Applicant of Cited Document	Date of Publication of Cited Document MM-DD-YYYY

FOREIGN PATENT DOCUMENTS						
Examiner Initials*	Cited No. <sup>1</sup>	Foreign Patent Document		Name of Patentee or Applicant of Cited Document	Date of Publication of Cited Document MM-DD-YYYY	Pages, Columns, Lines Where Relevant Info. Appear

OTHER DOCUMENTS (Including Author, Title, Date, Pertinent Pages, Etc.)						
<i>Op</i>	Despont et al.: "Wafer-Scale Microdevice Transfer/Interconnect: From A New Integration Method To Its Application In An AFM-Based Data-Storage System", 2003 IEEE, 12 <sup>th</sup> International Conference on Solid State Sensors, Actuators and Microsystems, Boston, June 8-12, 2003, pp. 1907-1910.					
	Wada et al.: "Fine Pitch Micro Probe Tips Using Thin Film Amorphous Alloy Under The Micromachining Fabrication Technology, Advantest Laboratories Ltd., Precision and Intelligence Laboratories, Tokyo Institute of Technology, 6/6/2001.					

EXAMINER <i>C. J. Arbes</i>	DATE CONSIDERED <i>4/11/05</i>
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